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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re the Application of: NAKATA, Yoshihiro et al.

Group Art Unit: 1771

Serial No.: 10/807,174

Examiner: Hai VO

Filed: March 24, 2004

P.T.O. Confirmation No.: 4205

For. **SILICON-BASED COMPOSITION, LOW DIELECTRIC CONSTANT FILM,
SEMICONDUCTOR DEVICE, AND METHOD FOR PRODUCING LOW
DIELECTRIC CONSTANT FILM**

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 28, 2007

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated November 28, 2006 for one month, from February 28, 2007 to March 28, 2007.

Attached please find a check in the amount of \$120.00 to cover the cost of the extension for a large entity. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 01-2340.

Respectfully submitted,
ARMSTRONG, KRATZ, QUINTOS,
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PATENT TRADEMARK OFFICE